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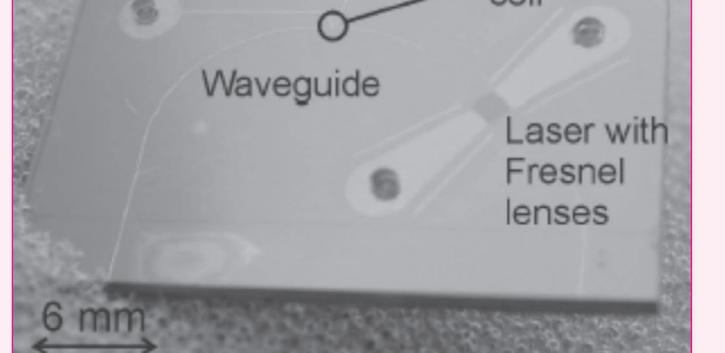


Thermoplastic Polymer for Imprinting

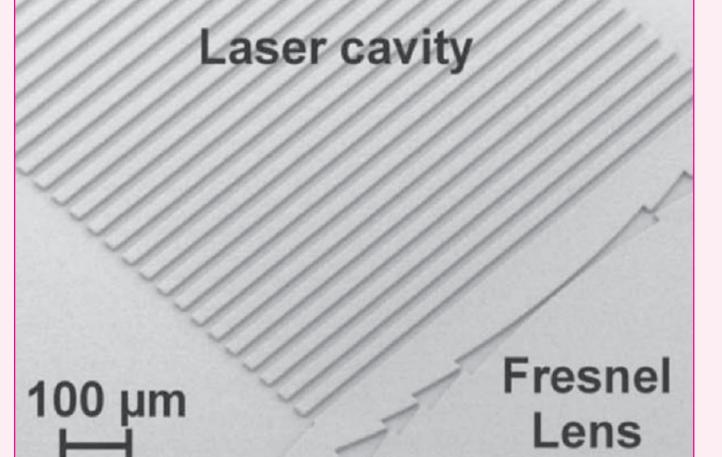
mr-I T85 – New Polymer for lab-on-a-chip, optical and bio applications

Microfluidics Absorbance

The new mr-I T85 series has been developed preferably for permanent applications



Complete lab-on-a-chip device for absorption measurements, all components imprinted in one layer of mr-I T85 (courtesy of MIC / TU Denmark)



in lab-on-a-chip systems, microfluidics, and microoptical components.

Unique features

- [–] Unpolar thermoplastic
- Excellent film quality
- ⁻ Beneficial flow behaviour during imprinting, low imprint pressure
- Excellent UV and optical transparency
- High plasma etch resistance
 - [–] comparable to novolak-based photoresists
 - ⁻ selectivity to silicon 9:1 (Si / mr-I T85)
- ⁻ High chemical stability

Applications

- [–] Lab-on-a-chip systems
- Bio applications
- [–] Microfluidics
- [–] Microoptical elements
- Wave guides
- [–] Single and multilayer systems
- [–] Mask for pattern transfer processes

Microfluidic dye laser and Fresnel lens imprinted in mr-I T85 (courtesy of MIC / TU Denmark)

Photonic wave guide filter fabricated using mr-I T85, 320 nm deep holes transferred into silicon (200 nm diameter) (courtesy of MIC / TU Denmark)

[–] high resistance to acids, bases and polar solvents

no interactions with conventional photoresists

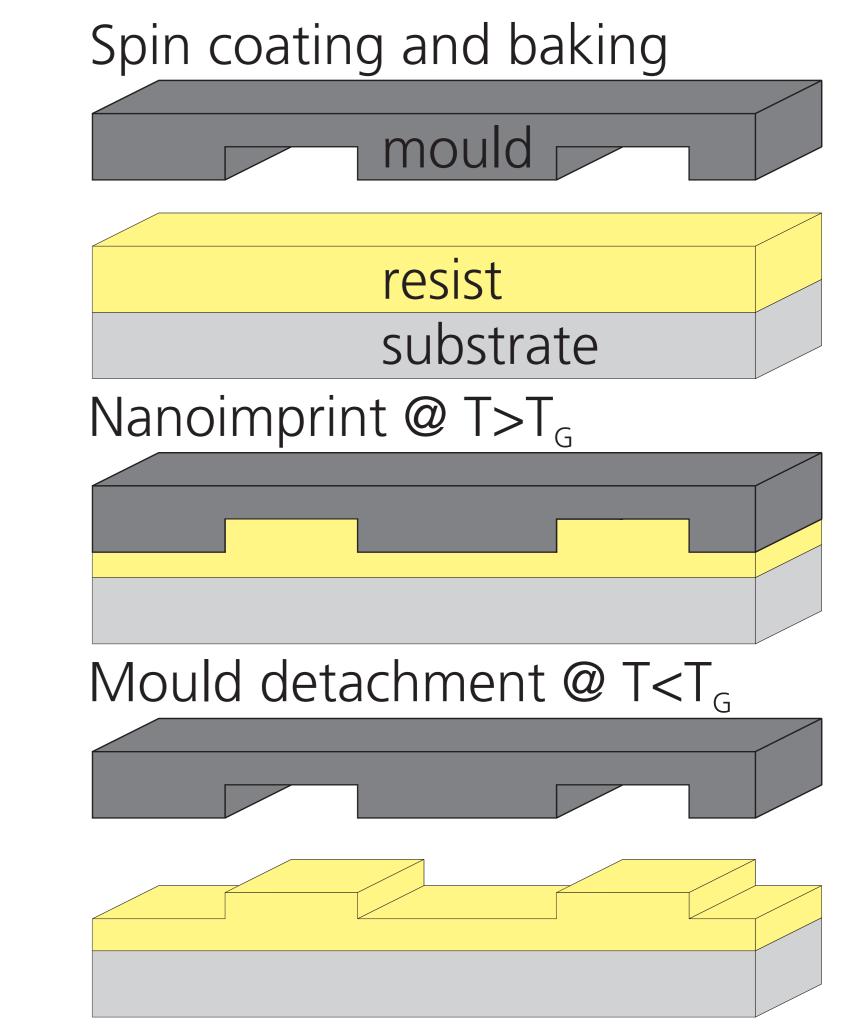
Technical Data

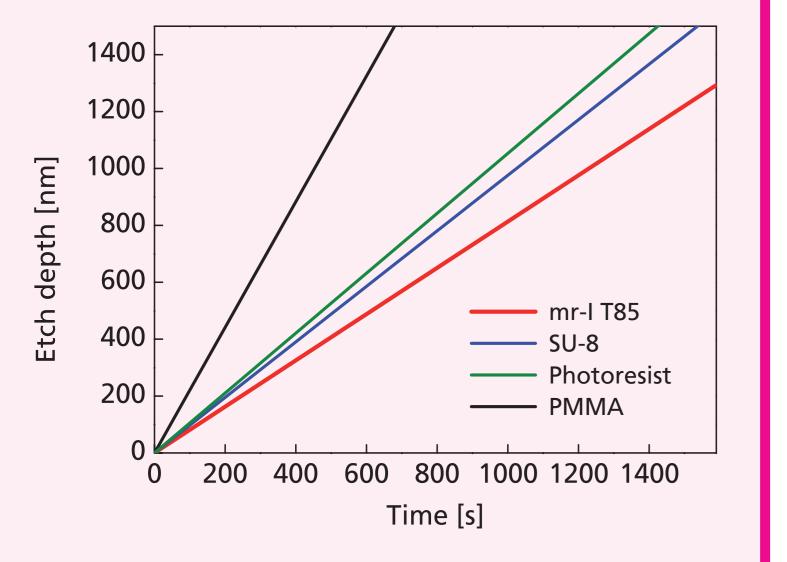
Glass transition temperature	85 °C
mprinting conditions	130 – 150 °C
Low pressure	5 – 20 bar

Ready-to-use solutions for various film thicknesses

Туре	Thickness ¹⁾
mr-I T85-0.3	300 nm

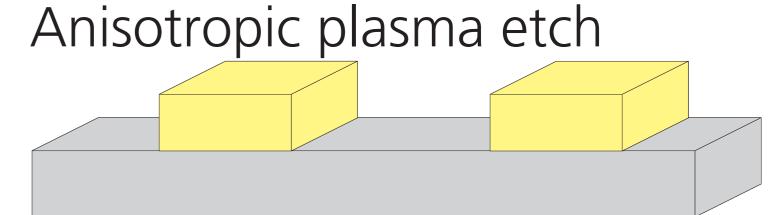
Process Flow





Etch depth as a function of time, SF_{c}/O_{2} plasma

mr-I T85-1.0 1.0 µm mr-I T85-5.0 5.0 µm ¹⁾ 3000 rpm, 30 s



Feature sizes can be imprinted ranging from sub-100 nm to 100 μ m. *micro resist technology* provides ready-to-use solutions for film thicknesses from 100 nm to 20 μ m.